

Ref #	Hits	Search Query	DBs	Default Operator	Plurals	Time Stamp
L1	10252	(method process manufactur\$3 fabricat\$3) near5 (mems micro\$1electro\$1mechanical)	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/12/11 13:16
L2	8468	L1 not (@rlad>"20040419" @ad>"20040419")	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2005/12/11 13:32
L3	5765	L2 and (mov\$3 displac\$5 deflect\$4 micro\$1mover)	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/12/11 13:35
L4	4027	L3 and (polymer\$2 thermoplastic thermoset pmma epoxy photoresist resist composition coat\$3)	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/12/11 13:16
L5	734	L4 and (polymer\$2 thermoplastic thermoset pmma epoxy photoresist resist composition coat\$3) with (selective\$2 align\$4)	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/12/11 13:33
L6	596	L5 and (polymer\$2 thermoplastic thermoset pmma epoxy photoresist resist composition coat\$3) with (pattern\$3 etch\$3)	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/12/11 13:53
L7	16	L6 and (cars atomic adj resolution adj storage)	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/12/11 13:16
L8	600432	(cars atomic adj resolution adj storage cps contact adj probe)	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/12/11 13:32
L9	576534	8 not (@rlad>"20040419" @ad>"20040419")	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2005/12/11 13:32
L10	7908	9 and (polymer\$2 thermoplastic thermoset pmma polymethylmethacrylate organic composition coat\$3) with (selective\$2 align\$4)	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/12/11 13:34

L11	4060	10 and (mov\$3 movable cantilever displac\$5 deflect\$4 micro\$1mover)	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/12/11 13:35
L12	8107	(mems micro\$1electro\$1mechanical) and data near2 stor\$4	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/12/11 13:38
L13	50	11 and L12	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/12/11 13:37
L14	50	13 and (mems micro\$1electro\$1mechanical) and data near2 stor\$4	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/12/11 13:38
L15	392	6 and plasma	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/12/11 14:11
L16	17	15 and hard\$4 and glass adj transition	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/12/11 13:55
S1	4	((("5116457") or ("6,587,408") or ("6,592,696") or ("6,594,057"))).PN. or (2003/0160540).CCLS.	US-PGPUB; USPAT; EPO; JPO; IBM_TDB	OR	OFF	2005/12/11 11:24
S2	1	("20030160540").PN.	US-PGPUB	OR	OFF	2005/12/09 15:18
S3	1	("20050135203").PN.	US-PGPUB	OR	OFF	2005/12/09 15:18
S4	8105	(mems micro\$1electro\$1mechanical) and data near2 stor\$4	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/12/11 13:36
S5	727	S4 and (cars atomic adj resolution adj storage)	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/12/11 13:31
S6	656	S5 and (mov\$3 displac\$5 deflect\$4 micro\$1mover)	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/12/09 18:20

S7	577	S6 not (@rlad>"20040419" @ad>"20040419")	US-PGPUB; USPAT; EPO; JPO	OR	OFF	2005/12/09 18:21
S8	1	S7 and (mov\$3 displac\$5 deflect\$4 micro\$1mover) same (selective\$2 align\$4) with (polymer\$2 thermoplastic thermoset pmma epoxy photoresist resist composition coat\$3)	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/12/09 17:53
S9	0	S7 and (mov\$3 displac\$5 deflect\$4 micro\$1mover) same (pattern\$3 etch\$3) with (polymer\$2 thermoplastic thermoset pmma epoxy photoresist resist composition coat\$3)	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/12/09 17:54
S10	73	S7 and (mov\$3 displac\$5 deflect\$4 micro\$1mover) same (polymer\$2 thermoplastic thermoset pmma epoxy photoresist resist composition coat\$3)	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/12/09 17:54
S11	73	S10 and (polymer\$2 thermoplastic thermoset pmma epoxy photoresist resist composition coat\$3)	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/12/09 18:23
S12	91	S7 and (method process manufactur\$3 fabricat\$3) near5 (mems micro\$1electro\$1mechanical)	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/12/09 18:20
S13	55	S12 not S11	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/12/09 18:10
S14	10244	(method process manufactur\$3 fabricat\$3) near5 (mems micro\$1electro\$1mechanical)	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/12/09 18:20
S15	7508	S14 not (@rlad>"20040419" @ad>"20040419")	US-PGPUB; USPAT; EPO; JPO	OR	OFF	2005/12/09 18:21
S16	8466	S14 not (@rlad>"20040419" @ad>"20040419")	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2005/12/09 18:22
S17	5763	S16 and (mov\$3 displac\$5 deflect\$4 micro\$1mover)	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/12/09 18:22

S18	4026	S17 and (polymer\$2 thermoplastic thermoset pmma epoxy photoresist resist composition coat\$3)	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/12/09 18:23
S19	733	S18 and (polymer\$2 thermoplastic thermoset pmma epoxy photoresist resist composition coat\$3) with (selective\$2 align\$4)	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/12/09 18:25
S20	596	S19 and (polymer\$2 thermoplastic thermoset pmma epoxy photoresist resist composition coat\$3) with (pattern\$3 etch\$3)	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/12/09 18:25
S21	16	S20 and (cars atomic adj resolution adj storage)	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/12/11 13:16